

**Notice of References Cited**

Application/Control No.

09/470,650

Applicant(s)/Patent Under  
Reexamination  
FIGURA ET AL.

Examiner

Lisa A Kilday

Art Unit

2829

Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	G	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"A comparison of HDP oxide and Spin-On polymer for Intermetal dielectric applications in sub-half micron devices", Zheng et al., DUMIC conferencepp. 283-293 (pages 288, 290, and 292 are blank), 2/10/97
	V	"Diagnostic Investigation of Oxide etching in a commercial high-density plasma etcher", John Arnold, The American Physical Society, 10/21/96.
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.